

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**RECEIVED
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Applicant(s): Yee-Chung Fu
Assignee: Advanced Nano Systems, Inc.
Title: MEMS Scanning Mirror with Trenched Surface and Tapered Comb Teeth for Reducing Inertia and Deformation
Serial No.: 10/779,952 Filing Date: February 13, 2004
Examiner: Allan R. Wilson Group Art Unit: 2815
Docket No.: ANS-P105

San Jose, California
December 7, 2004

Commissioner For Patents
P.O. Box 1450
Alexandria VA 22313-1450

PRELIMINARY AMENDMENT

Dear Sir:

Prior to the examination of the above-identified application, please amend the above-identified application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 8 of this paper.